

Microelectronics and Nanotechnology - Shamsuddin Research Centre (MiNT-SRC),
 Block F5, Pejabat Pengurusan Penyelidikan, Inovasi, Pengkomersilandan Perundingan (ORICC)
 Universiti Tun Hussein Onn Malaysia,
 86400 Parit Raja, Batu Pahat, Johor,
 Malaysia.
 Website: mint.uthm.edu.my

RF & DC SPUTTERING BOOKING FORM

DATE : _____

NAME : _____

POSITION : _____

SUPERVISOR NAME : _____

INSTITUTION NAME : _____

ADDRESS : _____

PHONE NO (OFFICE) : _____ PHONE NO (MOBILE) : _____

EMAIL ADDRESS : _____

SAMPLE NO 1

Material of Sputter Target	_____
Sample Size	Length : _____ (mm) Thickness : _____ (mm) Width : _____ (mm) *Maximum: length x width = 5 cm x 5 cm.
Material of Substrate	_____
No of Sample/deposition	_____
Estimate no of parameters	Deposition Power: Deposition Temperature: DC bias voltage: Working Pressure: Deposition rate: Desired Thickness:

SAMPLE NO2

Material of Sputter Target	_____
Sample Size	Length : _____ (mm) Thickness : _____ (mm) Width : _____ (mm) *Maximum: length x width = 5 cm x 5 cm.
Material of Substrate	_____
No of Sample/deposition	_____
Estimate no of parameters	Deposition Power: Deposition Temperature: DC bias voltage: Working Pressure: Deposition rate: Desired Thickness:

Schematic Diagram

Brief Process Details.


Note:

1. Please add the number of box if it is not enough.
2. Please fill this form and email to faezahana@uthm.edu.my
3. Rate for RF & DC Sputtering System:
 - RM200.00 /hours + gst 6% (for universities)
 - RM300.00 /hours + gst 6% (for industries)
4. Permission use of RF Sputtering System is given after approval or a guarantee of payment / payment completed.

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graph TD; Client1[Client] --> Booking[BOOKING<br/>1. RF & DC Sputtering booking with PIC (Dr. Nafarizal:<br/>07-4538611, 0197170001; nafa@uthm.edu.my)<br/>2. Client fills booking form]; Booking --> MiNTSRC1[MiNT-SRC]; MiNTSRC1 --> Quotation[QUOTATION<br/>Quotation send to client as requested in RF Sputtering booking<br/>form]; Quotation --> Client2[Client]; Client2 --> Guarantee[GUARANTEE LETTER<br/>Prepare a guarantee letter from client's institution to the Head of Mint-SRC which specifying payment details of testing,<br/>eg: grants, cash or etc.]; Guarantee --> MiNTSRC2[MiNT-SRC]; MiNTSRC2 --> Testing[TESTING<br/>RF Sputtering deposition conducted with agreed date and time]; Testing --> Client3[Client]; Client3 --> Payment[PAYMENT<br/>Confirm payment status of RF Sputtering]; Payment --> MiNTSRC3[MiNT-SRC]; MiNTSRC3 --> Result[RESULT<br/>RF Sputtering Deposition result given to client]; Result --> End[END];
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The flowchart illustrates the RF Sputtering process, involving a Client and MiNT-SRC. The process begins with the Client performing a **BOOKING**, which includes RF & DC Sputtering booking with PIC (Dr. Nafarizal: 07-4538611, 0197170001; nafa@uthm.edu.my) and filling out a booking form. This leads to MiNT-SRC sending a **QUOTATION** to the Client as requested in the RF Sputtering booking form. The Client then provides a **GUARANTEE LETTER** to MiNT-SRC, specifying payment details of testing, such as grants, cash, or etc. MiNT-SRC then conducts the **TESTING** (RF Sputtering deposition) with the agreed date and time. The Client confirms the **PAYMENT** status of RF Sputtering to MiNT-SRC. Finally, MiNT-SRC provides the **RESULT** (RF Sputtering Deposition result) to the Client, leading to the **END** of the process.

EXAMPLE GUARANTEE LETTER

 UTM UNIVERSITI TEKNOLOGI MALAYSIA	Fakulti Kejuruteraan Kimia Universiti Teknologi Malaysia 81310 Johor Bahru Johor, Malaysia
Tel: +(6)XXXXXX Faks: +(6)XXXXXX http://www.cheme.utm.my Emel: info@cheme.utm.my	
RUJUKAN KAMI:	2nd March 2014
RUJUKAN TUAN:	
Microelectronic and Nanotechnology (MiNT-SRC), Office for Research, Innovation, Commercialization & Consultancy Management (ORICC) Universiti Tun Hussein Onn Malaysia, 86400 Batu Pahat, Johor. (u/p: Nurhafizah Ruslan)	
Tuan,	
PERMOHONAN PEMBAYARAN FESEM MENGGUNAKAN PROJEK VOT XXXXXXXXXX	
Dengan segala hormatnya saya merujuk perkara diatas.	
2. Selaku ketua projek bagi vot XXX saya ingin memohon kelulusan dari pihak UTHM untuk membayar alatan sewaan FESEM dengan menggunakan peruntukan dari Vot. XXXXXXXXXX	
3. Butiran penggunaan alat FESEM adalah seperti berikut: Tarikh Penggunaan : XXXXXX Bilangan Sample: X Jumlah Bayaran : XXXX	
4. Oleh yang demikian, saya memohon agar pihak tuan dapat meluluskan permohonan ini. Segala kerjasama dari pihak tuan amat dihargai dan didahului dengan ucapan terima kasih.	
Sekian, <i>wassalam</i> .	
Yang benar,	
..... Assoc.Prof. XXXXXXXXXXXX Ketua Projek Vot XXXXXXXXXXXX Jabatan Kejuruteraan Polimer, Fakulti Kejuruteraan Kimia,UTM Universiti Teknologi Malaysia	
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MiNT-SRC's LOCATION

